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## APPLICANTS

Keiji Yoshimura, Tochigi, JAPAN;

## \*\* CONTINUING DATA

*None*

## \*\* FOREIGN APPLICATIONS

JAPAN 2000/302162 10/02/2000

JAPAN 2001/089762 03/27/2001

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 11/14/2001

Foreign Priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY	SHEETS	TOTAL CLAIMS	INDEPENDENT CLAIMS
35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Not after Allowance	JAPAN	DRAWING 15	27	16
Verified and Acknowledged	<i>Yoshimura's Signature</i> Initials			18	2

## ADDRESS

05514

## TITLE

Exposure apparatus, semiconductor device manufacturing method, exposure apparatus maintenance method and semiconductor manufacturing factory

FILING FEE RECEIVED 1396	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit
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